

Form PTO-1449

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	AA						
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		Document Number	Date	Country	Class	Subclass	Translation
	AF	WO 01/11063 A2	04/04/02	WIPO			Yes
	AG						No
OTHER REFERENCES (including Author, Title, Date, Periodical Pages, Etc.)							
\$2	AB	'Atomic Layer Deposition of SiO <sub>2</sub> Using Catalyzed And Uncatalyzed Self-Limiting Surface Reactions'; J.W. Klaus et al; Surface Review and Letters, Vol. 6, Nos. 3 & 4 (1999) pp. 435-448					
	AI	'Self-limiting chemical vapor deposition of an ultra-thin silicon oxide film using tri-(tert-butyl)silanol'; K.A. Miller et al; Thin Solid Films 397 (2001) pp. 78-82					
	AJ	'Reactive Deposition of Metal Thin Films within Porous Supports from Supercritical Fluids'; Neil E. Fernandes et al; Chem Mater. 2001; 13, pp. 2023-2031					
	AK	'Supercritical CO <sub>2</sub> Processing for Submicron Imaging of Fluoropolymers'; Narayen Sunderarajan et al; Chem. Mater. 2000; 12; pg. 41-46					
	AL	'Supercritical carbon dioxide assisted aerosolization for thin film deposition, fine powder generation, and drug delivery'; C.Y. Xu et al; P.T. Anastas; T.C. Williamson, Green Chemistry, 5, pp. 313-335; Oxford University Press, Oxford 1998					
\$2	AM	'Supercritical Fluid Transport-Chemical Deposition of Films'; Brian N. Hansen et al; Chem Mater. 1992; 4; pp. 749-752					
EXAMINER				DATE CONSIDERED	6/1/04		
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							